

**EXPEDITED PROCEDURE**  
**Examining Group Number 2800**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

|                  |  |                 |                       |
|------------------|--|-----------------|-----------------------|
| Applicant:       | Craig K. Carlson-Stevermer                           | Examiner:       | Jermele M. Hollington |
| Serial No.:      | 10/622,849   | Group Art Unit: | 2829                  |
| Filed:           | July 18, 2003  | Docket No.:     | A126.114.102          |
| <b>Due Date:</b> | <b>February 22, 2007</b>                             |                 |                       |
| Title:           | WAFER STAGING PLATFORM FOR A WAFER INSPECTION SYSTEM |                 |                       |

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**AMENDMENT AND RESPONSE UNDER 37 C.F.R. 1.116**

**Mail Stop AF**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

This is responsive to the Final Office Action mailed November 22, 2006. Please amend the above-identified patent application as follows: